



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Hashim, et al.

Serial No.: 09/138,429

Filed: August 24, 1998

For: Collimated and Long Throw
Magnetron Sputtering of
Nickel/Iron Films for Magnetic
Recording Head Applications

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Group Art Unit: 1753

Examiner: Mercado, J.

Confirmation No.: 4066

#15/E
10-9-01A

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Box RCE
Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

CERTIFICATE UNDER 37 CFR 1.10

I hereby certify that this correspondence and the documents referred to as attached therein are being deposited on September 12, 2001 with the United States Postal Service in an envelope as "Express Mail Post Office to Addressee," mailing label No. EL849164179US addressed to: Commissioner for Patents, Box RCE, Washington, D.C. 20231.

9/12/01
Date

Signature

PRELIMINARY AMENDMENT

Applicants, in accordance with 37 C.F.R. §1.114(c), request consideration of the following amendments prior to the examination of the attached Request for Continued Prosecution of the above identified application.

In the claims:

Please cancel claims 1 – 3, 5 – 6, 15 – 16, and ~~18~~ – 20.

1. (Cancelled) An apparatus for depositing a magnetic film, comprising:
a sputtering chamber containing a target, a substrate support having a surface that is separated from the target, and a grounded collimator positioned between the target and the substrate support; and
an annular magnet array disposed within the chamber to form a magnetic field that is substantially parallel to the surface of the substrate support, the annular magnet array being concentrically positioned about the surface of the substrate support.